

# Mass Flow Controller for DeviceNet<sup>TM</sup> **Instruction Manual**

# **MC-5000L** Series

#### **Safety Precautions**

#### WARNING Incorrect handling may cause death or injury /!\

- (1) Before connecting the fittings, check that no damage or defects are found on the fittings. Make connections properly and make sure that a leak test is conducted before actual operation to prevent fluid from leaking into the atmosphere (Hereinafter, the fluid used is referred as "gas" or "fluid").
- (2) DO NOT apply any corrosive fluid to materials exposed to gas. Corrosion may cause gas to leak into the atmosphere.
- (3) This device is not designed as an explosion proof structure. DO NOT use this device in a place where explosion-proof structures are required. Doing so may cause fire or explosion.

#### Incorrect handling may lead to medium or slight injury or may CAUTION

- cause damage to, or loss of, facilities or equipment Observe the precautions listed in the WARNING (above).
- Strictly observe the electrical specifications. Not doing so may cause fire, damage to (2) sensors or malfunction.
- This device is not designed to be waterproof. DO NOT locate this device outdoors or in a (3) place where it may be splashed with water. Doing so may cause fire, trouble, or malfunction of the device.
- (4) DO NOT modify this device. It may cause fire or other problems.
- This device is not designed to handle hot swap. Please avoid attaching and removing the (5) power supply connector and interface connector with the power switched on. Attachment and/or removal with the power on may result in failure of the device.
- This device is a precious device, please handle it carefully. Dropping down or handling it carelessly will cause damage. Please use assist instrument while moving or setting the (6) device.
- (7) Regular maintenance is recommended for steady use of this device (Recommended proofreading frequency is once a year).

#### 1. Introduction

This manual explains basic operation of the MC-5000L series (Hereinafter referred as "MFC"). MFC is equipped with a network interface, and can be operated by connecting to a network environment of Device Net  $^{TM}$ .

Since MFC is a slave device, please prepare a master device of Device Net TM network interface.

The device profile follows the MFC profile in ODVA specification. Please go through the ODVA specification and device profile manual of MC-5000L for proper use.

#### 2. Summary

The MFC is high performance mass flow controller for gas using thermal flow sensor and high response piezoelectric valve. In the MFC model, MO type and MC type are available depending on the kind of valve operation mode. Also, MFC interface employs Device Net<sup>™</sup> network, so MFC is compatible with other makers.

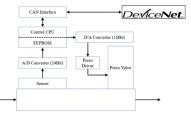
#### 3. Features

The MFC is the following features.

- (1) LINTEC's proprietary ambient temperature compensation type flow sensor is carried. Low sensor temperature, long-time steady monitor, and few problems such as degradation of gas to be monitored.
  - The effect of ambient temperature is less because the sensor temperature is kept at the ambient temperature.
- Steady temperature distribution of sensor and high-speed response. (2) Digital computing system with microprocessor and high-resolution A/D, D/A converter is carried.
  - High functionality.
  - By setting of device number (address), multiple devices can be controlled through a single interface
  - · Many additional are provided as standard, e.g., totalizer function, zero adjust, ramping function.
- MFC employs DeviceNet<sup>TM</sup> network protocol. (3)
- (4) Small dead space structure using a diaphragm valve.
- (5) Single power supply 11 to 25VDC.
- (6) Superior corrosion resistant sealing materials make maintenance easy. Metal seals (Au).
- Particle-free structure.
- By using a metal case and various types of filters, steady operation can achieve (8)even in an environment of high-frequency noise and stationary magnetic field. (9) Based on RoHS.

#### 4. Structure

The MFC consists of sensors, bypass, valves, and a microcomputer for signal processing. A digital PID feedback control system controls the valve action so that flow rate output from the sensor agrees with flow rate setting value.



### 5. Specification / Dimensions

1) Specification				
Name	MC 51001	Mass Flow Controller	MC 52501	
Model Flow rate range	MC-5100L	MC-5200L	MC-5250L	
(N2 conversion)	10SCCM to 5 SLM	~20SLM	~50SLM	
Valve operation mode	Normally open / Normally closed			
Surface treatment	Precision polishing			
Minimum controllable flow rate		2%F.S.		
Accuracy	100% F.S. to 10% F.S. ±1.0% S.P. 10% F.S. to 2% F.S. ±0.1% F.S.			
Repeatability		±0.2%F.S.		
Response time		1 second (Typical)		
Operating differential pressure	50 to 300kPa	Normally open 50 to 300kPa (~10SLM) 100 to 300kPa (10 to 20SLM) Normally closed 100 to 300kPa (~10SLM) 200 to 300kPa (10 to 20SLM)	100 to 300kPa (~30SLM) 150 to 300kPa (~50SLM)	
Maximum operating pressure (Note1)		300kPa(G)	-	
Withstanding pressure	1	1MPa(G)		
Operating temperature & Humidity	5 to 50 °C 0 to 8	5 to 50 °C 0 to 80% RH (Condensation should be avoided)		
Storage temperature & Humidity	0 to 60 °C 0 to 80% RH (Condensation should be avoided)			
Leak integrity	Less than $1 \times 10^{-11}$ Pa · m <sup>3</sup> /sec (He)			
Mounting direction	Free			
Wetted materials	Stainless steel 316L, PCTFE, PTFE, Au			
Seal Materials	Au			
Actuator		Piezoelectric actuator		
Fittings	6.35VCR (106mm, 124mm) 1.125 W-Seal 79.8mm, 1.125 W-Seal 92mm			
Power supply	11 to 25VDC (5VA max.)			
Digital interface	DeviceNet <sup>TM</sup>			
Optional	B: Liquefied gas, G: Minimum control flow rate 0.5%F.S. E: Small Range Control 1 to 10SCCM in nitrogen I: Value is closed at below 2% setting. M: Applied to CIE3			
Weight	5. Varve 15 01080	J: Valve is closed at below 2% setting, M: Applied to CIF3 Approx. 1kg		
Name		Mass Flow Controller		
Model	MC-546		C-5470I	
	MIC-340	M	C-5470L	
Flow rate range (N2 conversion)	~150 SI		200SLM	
Valve operation mode		Normally closed		
Surface treatment		Precision polishing		
Minimum controllable flow rate		2%F.S.		
Accuracy	100% F.S. to $\pm 1.0\%$ S 35% F.S. to $\pm 0.35\%$ S	S.P. 2%F.S.	1.0%F.S.	
Repeatability		±0.5%F.S.		
Response time		1 second (Typical)		
Operating differential	250 to 50	00kPa 350	) to 500kPa	
pressure				
Maximum operating pressure (Note1)		500kPa(G)		
Withstanding pressure	1	1MPa(G)		
Operating temperature & Humidity	1MPa(G)   5 to 50 °C·0 to 80% RH (Condensation should be avoided)   0 to 60 °C·0 to 80% RH (Condensation should be avoided)			
Storage temperature & Humidity				
Leak integrity	Ies	s than $1 \times 10^{-11}$ Pa · m <sup>3</sup> /sec (	He)	
Mounting direction		Free		
Wetted materials	Stainless steel 3	04, Stainless steel 316L, Te	eflon, Viton, Au	
Seal Materials		Au	. , .	
Actuator	Piezoelectric actuator			
Fittings	6 35111P 156mm 0 52111P 163 4mm			

Digital interface Device Net<sup>TM</sup> Optional J: Valve is closed at below 2% setting Weight Approx. 1.4kg Note1)There is a possibility that the gas does not flow in case of the gas pressure of more than 490kPa was used on the MC-5250L- MO /NO.

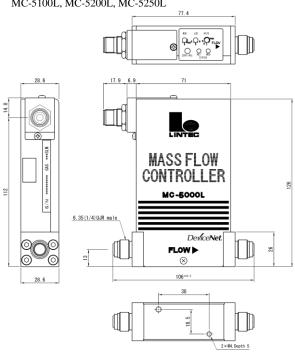
6.35UJR156mm, 9.52UJR163.4mm

11 to 25VDC (5VA max.)

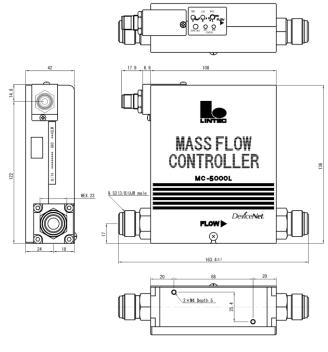
Connect the MFC to the frame ground.

Fittings Power supply

#### (2) Dimensions MC-5100L, MC-5200L, MC-5250L



#### MC-5460L, MC-5470L



### 6. Ordering information

MC-510*L	- <u>MO</u> -	4JR1	AA0A0	– <u>dd</u> –	- <u>ee</u> -	- <u>ff</u>
[1]	[2]	[3]	[4]	[5]	[6]	[7]
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- [1] Series model MC: Mass Flow Controller Series MC-5100L, MC-5200L, MC-5250L, MC-5460L, MC-5470L
- \* Power connector orientation 0: Side direction, 1: Upper direction [2] Valve mode
- MO: Normally open (Precision polishing)
- MC: Normally close (Precision polishing)
- [3] Fitting size
- 4VR1:6.35VCR106, 4VR2:6.35VCR124, 4SWL:6.35SWL
- SPW3: Surface mount 1.1.25W-Seal 79.8mm, SPW4: Surface mount 1.125W-Seal 92mm 6JR3: 9.52UJR163.4mm, 4JR4: 6.35UJR156mm (Applied to MC-5460L and MC-5470L) ※ Please consult for more information.

[4] Optional

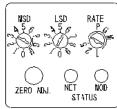
- B: Applied to liquefied gas, E: Small Range Control (1 to 4SCCM in nitrogen) G: Wide Range specifications (Control range 0.5 to 100 %F.S.)
- J: Valve is closed at below 2% setting, M: Applied to CIF3
- \* Default setting is labeled "AA0A0". Please consult for more information.
- [5] Gas type
- [6] Full scale flow rate [7] Flow rate unit
- SCCM (0 °C standard), SLM (0 °C standard)

### 7. Connection

(1) DeviceNet<sup>TM</sup> connector: Pin type micro connector (IEC60947-5-2)

Pin No.	Signal name	Function	
1	Drain	Shield	
2	V+	Power supply 11 to 25VDC (+)	
3	V-	Power supply (-)	
4	CAN_H	CAN interface HI	
5	CAN L	CAN interface LO	

(2) Rotary switch, LED (on top of the MFC housing)



NET	Network Status	Network Status LED
MOD	Module Status	Module Status LED
ZERO ADJ.	Zero Adjustment	Zero Adjustment button

Display	Name	Description	Default
MSD LSD	Node Address	Node LSD a digit in tens place	
RATE	Data Rate	Baud rate switch 1: 125 kbps 2: 250 kbps 5: 500 kbps Otherwise: Software set mode	5

#### 8. Operation

#### Procedure

- 1) This product is packed in a clean room before shipment. Please break the seals in a clean room after taking it out of its box.
- Check the gas type and flow rate, and check the direction of the gas flow and the MFC before installation. 2)
- Check for gas leaks from the tubing with a helium (He) leak detector. 3) 4) Prepare a master for Device Net<sup>TM</sup> and connect specified power, cable and connector.
- 5) Connect to the network.
- Turn on power supply and let the equipment warm up for at least 5 minutes 6) (Recommended time: 30min).
- Please power on the MFC for 30 mins, then conduct zero-point adjustment 7) without gas flowing by pressing button on the top of device or software.
- 8) Device starts controlling flow after inputting setting value by software and introducing gas with the specific pressure.
- 9) Complete shut off cannot be achieved with the mass flow controller. If complete shut off is desired, a shut-off valve should be installed. 10)
- When a highly reactive gas is used, thoroughly purge all foreign matter from the tubing and the MFC before operation.
- 11) When contaminated gas is used, install a filter at the equipment inlet.

#### 9. Product warranty

#### (1) Period

This product is guaranteed for a period of 1 year from date of shipment. Defects are repaired according to the following regulations.

(2) Scope

Warranty coverage is restricted to this product only. Any other damage caused by this product is not covered.

- (3) Disclaimer facts
  - The following repairs are not covered by the warranty:
    - 1) Failure caused by by-product of fluid used.
    - 2) Failure caused by misuse (including careless operation) or incorrect repair or modification.
    - 3) Failure caused by dropping after purchasing.
    - 4) Failure caused by a natural disasters.
  - Even if the warranty period is still in effect, the following items may not be repaired.
    - 1) When the kind of fluid used in the product is unclear. 2) The product is returned with fluid remaining inside and safety cannot be confirmed.

The MFC is a precision instrument. Control may become unstable if electric noise, temperature change of fluid, pulsation of fluid pressure etc. occurs. Please be forewarned.

This instruction manual is subject to revision without notice.

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